

Day : Wednesday

Date: 6/28/2006

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**PALM INTRANET**
**Inventor Name Search Result**

Your Search was:

Last Name = MITAMURA

First Name = NOBUAKI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<a href="#">07557574</a>	<a href="#">5030017</a>	150	07/24/1990	ROLLING BEARING	MITAMURA, NOBUAKI
<a href="#">07560445</a>	<a href="#">5084116</a>	150	07/31/1990	ROLLING CONTACT ELEMENT STEEL AND ROLLING BEARING MADE THEREOF	MITAMURA, NOBUAKI
<a href="#">07572480</a>	<a href="#">5085733</a>	150	08/23/1990	ROLLING CONTACT PARTS STEEL AND ROLLING BEARING MADE THEREOF	MITAMURA, NOBUAKI
<a href="#">07915503</a>	Not Issued	161	07/20/1992	BALL AND ROLLER BEARING	MITAMURA, NOBUAKI
<a href="#">07946638</a>	<a href="#">5338377</a>	150	09/18/1992	BALL-AND-ROLLER BEARING	MITAMURA, NOBUAKI
<a href="#">08134588</a>	<a href="#">5427457</a>	150	10/12/1993	ROLLING BEARING	MITAMURA, NOBUAKI
<a href="#">08242668</a>	<a href="#">5413643</a>	150	05/13/1994	ROLLING BEARING	MITAMURA, NOBUAKI
<a href="#">08374179</a>	Not Issued	166	01/18/1995	TOROIDAL-TYPE CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI
<a href="#">08512419</a>	<a href="#">5660647</a>	150	08/08/1995	ROLLING BEARING WITH IMPROVED WEAR RESISTANCE	MITAMURA, NOBUAKI
<a href="#">08519643</a>	<a href="#">5626974</a>	150	08/25/1995	ROLLING BEARING FOR USE UNDER HIGH TEMPERATURE CONDITIONS	MITAMURA, NOBUAKI
<a href="#">08536773</a>	<a href="#">5672014</a>	150	09/29/1995	ROLLING BEARINGS	MITAMURA, NOBUAKI
<a href="#">08542828</a>	<a href="#">5853660</a>	150	10/13/1995	A ROLLING BEARING MADE OF IMPROVED BEARING STEEL	MITAMURA, NOBUAKI
<a href="#">08683195</a>	<a href="#">5958155</a>	150	07/18/1996	PROCESS FOR PRODUCING	MITAMURA,

				THIN FILM	NOBUAKI
<u>08745635</u>	<u>5855531</u>	150	11/08/1996	COMPONENT PARTS OF A TOROIDAL-TYPE CONTINUOUSLY VARIABLE TRANSMISSION HAVING IMPROVED LIFE	MITAMURA, NOBUAKI
<u>08763883</u>	<u>5887015</u>	150	12/11/1996	HEATER MECHANISM FOR CRYSTAL PULLING APPARATUS	MITAMURA, NOBUAKI
<u>08877950</u>	<u>5989694</u>	150	06/17/1997	ROLLING BEARING	MITAMURA, NOBUAKI
<u>08955294</u>	Not Issued	164	10/21/1997	ROLLING BEARING MADE OF IMPROVED BEARING STEEL	MITAMURA, NOBUAKI
<u>09098980</u>	<u>6171414</u>	150	06/17/1998	ROLLING BEARING	MITAMURA, NOBUAKI
<u>09108174</u>	<u>6174257</u>	150	07/01/1998	TOROIDAL TYPE CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI
<u>09181911</u>	<u>6174258</u>	150	10/29/1998	TOROIDAL-TYPE CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI
<u>09183630</u>	<u>6066068</u>	150	10/30/1998	TOROIDAL TYPE CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI
<u>09187607</u>	<u>6165100</u>	150	11/06/1998	HIGH-CLEANNESS STEEL AND TOROIDAL TYPE CONTINUOUSLY VARIABLE TRANSMISSION INCLUDING COMPONENTS SUCH AS INPUT/OUTPUT DISCS, POWER ROLLER AND CAM DISC USING THE HIGH-CLEANNESS STEEL	MITAMURA, NOBUAKI
<u>09226032</u>	<u>6174085</u>	150	01/05/1999	LINEAR GUIDE BEARING DEVICE	MITAMURA, NOBUAKI
<u>09235052</u>	<u>6196946</u>	150	01/21/1999	POWER ROLLER BEARING OF TOROIDAL TYPE CONTINUOUSLY VARIABLE TRANSMISSION AND METHOD OF MANUFACTURING POWER ROLLER BEARING OF TOROIDAL TYPE CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI

<u>09245931</u>	Not Issued	161	02/08/1999	TEMPERATURE- INDEPENDENT OPTICAL ELEMENT	MITAMURA, NOBUAKI
<u>09272731</u>	6210542	150	11/04/1998	PROCESS FOR PRODUCING THIN FILM, THIN FILM AND OPTICAL INSTRUMENT INCLUDING THE SAME	MITAMURA, NOBUAKI
<u>09339238</u>	6332714	150	06/24/1999	INDUCTION-HARDENED ROLLING BEARING DEVICE	MITAMURA, NOBUAKI
<u>09344380</u>	6328669	150	06/25/1999	TOROIDAL TYPE CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI
<u>09349204</u>	6176806	150	07/07/1999	CAM DISK FOR TOROIDAL TYPE CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI
<u>09358554</u>	6478894	150	07/22/1999	ROLLING BEARING	MITAMURA, NOBUAKI
<u>09379748</u>	6152605	150	08/24/1999	BALL BEARING	MITAMURA, NOBUAKI
<u>09401917</u>	6358440	150	09/23/1999	PROCESS FOR PRODUCING THIN FILM, THIN FILM AND OPTICAL INSTRUMENT INCLUDING THE SAME	MITAMURA, NOBUAKI
<u>09697179</u>	6829053	150	10/27/2000	AIRGAP TYPE ETALON AND APPARATUS UTILIZING THE SAME	MITAMURA, NOBUAKI
<u>09886122</u>	6413188	150	06/22/2001	TOROIDAL TYPE CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI
<u>09939566</u>	6646805	150	08/28/2001	APPARATUS FOR VARIABLE WAVELENGTH DISPERSION AND WAVELENGTH DISPERSION SLOPE	MITAMURA, NOBUAKI
<u>09957413</u>	6426022	150	09/20/2001	PROCESS FOR PRODUCING THIN FILM, THIN FILM AND OPTICAL INSTRUMENT INCLUDING THE SAME	MITAMURA, NOBUAKI
<u>09984396</u>	6807335	150	10/30/2001	WAVELENGTH CHARACTERISTIC VARIABLE APPARATUS	MITAMURA, NOBUAKI
<u>10061307</u>	6826318	150	02/04/2002	VARIABLE POLARIZATION PLANE ROTATOR AND OPTICAL DEVICE USING SAME	MITAMURA, NOBUAKI
<u>10164438</u>	6900940	150	06/10/2002	OPTICAL APPARATUS AND	MITAMURA,

				DEVICE	NOBUAKI
<u>10278868</u>	Not Issued	41	10/24/2002	Device using a virtually-imaged phased array (VIPA) with an improved transmission wave characteristic of output light	MITAMURA, NOBUAKI
<u>10286779</u>	6862126	150	11/04/2002	TRANSMISSION WAVELENGTH CHARACTERISTICS VARIABLE OPTICAL ELEMENT, AND WAVELENGTH CHARACTERISTICS VARIABLE APPARATUS, OPTICAL AMPLIFIER, OPTICAL TRANSMISSION SYSTEM, AND CONTROL METHOD OF TRANSMISSION WAVELENGTH CHARACTERISTICS, USING SAME	MITAMURA, NOBUAKI
<u>10310900</u>	Not Issued	93	12/06/2002	ROLLING BEARING	MITAMURA, NOBUAKI
<u>10340842</u>	6909537	150	01/13/2003	DISPERSION COMPENSATOR WHOSE TRANSMISSION BAND IS FLATTENED	MITAMURA, NOBUAKI
<u>10341380</u>	6807008	150	01/14/2003	WAVELENGTH DISPERSION GENERATION APPARATUS, MULTI-FACED MIRROR USED FOR WAVELENGTH DISPERSION GENERATION APPARATUS, AND METHOD FOR MANUFACTURING THEREOF	MITAMURA, NOBUAKI
<u>10351376</u>	7016096	150	01/27/2003	TRANSMISSION WAVELENGTH CHARACTERISTICS VARIABLE OPTICAL ELEMENT, AND WAVELENGTH CHARACTERISTICS VARIABLE APPARATUS, OPTICAL AMPLIFIER, AND OPTICAL TRANSMISSION SYSTEM, USING SAME	MITAMURA, NOBUAKI
<u>10410342</u>	7037386	150	04/10/2003	ROLLING BEARING FOR CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI

<u>10414308</u>	6923576	150	04/16/2003	ROLLING BEARING AND BELT CONTINUOUSLY VARIABLE TRANSMISSION	MITAMURA, NOBUAKI
<u>10500580</u>	Not Issued	41	07/01/2004	AN SOI WAFER AND A METHOD FOR PRODUCING AN SOI WAFER	MITAMURA, NOBUAKI
<u>10510695</u>	Not Issued	41	10/08/2004	METHOD OF MANUFACTURING SILICON SINGLE CRYSTAL, SILICON SINGLE CRYSTAL AND SILICON WAFER	MITAMURA, NOBUAKI
<u>10512470</u>	Not Issued	20	10/26/2004	Silicon single crystal wafer and epitaxial wafer, and method for producing silicon single crystal	MITAMURA, NOBUAKI

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**Search Another: Inventor**

Last Name	First Name	
<input type="text" value="Mitamura"/>	<input type="text" value="Nobuaki"/>	<input type="button" value="Search"/>

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Day : Wednesday

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**PALM INTRANET**
**Inventor Name Search Result**

Your Search was:

Last Name = OHTA

First Name = TOMOHIKO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>08655810</u>	<u>5817171</u>	150	05/31/1996	APPARATUS AND METHOD FOR PRODUCING SINGLE CRYSTAL USING CZOCHRALSKI TECHNIQUE	OHTA, TOMOHIKO
<u>08666654</u>	<u>5704973</u>	150	06/18/1996	AN APPARATUS AND METHOD FOR THE UNIFORM DISTRIBUTION OF CRYSTAL DEFECTS UPON A SILICON SINGLE CRYSTAL	OHTA, TOMOHIKO
<u>08699719</u>	<u>5725661</u>	250	07/01/1996	EQUIPMENT FOR PRODUCING SILICON SINGLE CRYSTALS	OHTA, TOMOHIKO
<u>08760959</u>	<u>5766346</u>	150	12/05/1996	APPARATUS FOR PRODUCING SILICON SINGLE CRYSTAL	OHTA, TOMOHIKO
<u>08770499</u>	<u>5851283</u>	150	12/20/1996	METHOD AND APPARATUS FOR PRODUCTION OF SINGLE CRYSTAL	OHTA, TOMOHIKO
<u>08776776</u>	<u>5972106</u>	150	02/10/1997	DEVICE AND METHOD FOR PRODUCING SINGLE CRYSTAL	OHTA, TOMOHIKO
<u>08786340</u>	<u>5882398</u>	250	01/23/1997	METHOD OF MANUFACTURING SINGLE CRYSTAL OF SILICON	OHTA, TOMOHIKO
<u>08798472</u>	<u>5948163</u>	250	02/10/1997	APPARATUS FOR MANUFACTURING CRYSTALS ACCORDING TO THE CZOCHRALSKI METHOD, AND CRYSTALS MANUFACTURED BY THE MANUFACTURING METHOD	OHTA, TOMOHIKO
<u>09090400</u>	<u>5938842</u>	150	06/04/1998	METHOD FOR PRODUCING A SINGLE CRYSTAL USING	OHTA, TOMOHIKO

				CZOCHRALSKI TECHNIQUE	
<u>09125339</u>	<u>6071337</u>	150	08/13/1998	APPARATUS AND METHOD FOR PRODUCING CRYSTALS BY THE CZOCHRALSKI METHOD AND CRYSTALS PRODUCED BY THIS METHOD	OHTA, TOMOHIKO
<u>09270277</u>	<u>6153009</u>	150	03/16/1999	METHOD FOR PRODUCING A SILICON SINGLE CRYSTAL AND THE SILICON SINGLE CRYSTAL PRODUCED THEREBY	OHTA, TOMOHIKO
<u>09270453</u>	<u>6156119</u>	150	03/17/1999	SILICON SINGLE CRYSTAL AND METHOD FOR PRODUCING THE SAME	OHTA, TOMOHIKO
<u>09290261</u>	<u>6117231</u>	150	04/13/1999	METHOD OF MANUFACTURING SEMICONDUCTOR SILICON SINGLE CRYSTAL WAFER	OHTA, TOMOHIKO
<u>09328278</u>	<u>6190452</u>	150	06/08/1999	SILICON SINGLE CRYSTAL WAFER AND METHOD FOR PRODUCING IT	OHTA, TOMOHIKO
<u>09541462</u>	<u>7078203</u>	150	03/31/2000	ISOLATED DNA ENCODING CULLIN REGULATORS ROC1 AND ROC2, ISOLATED PROTEIND ENCODED BY THE SAME, AND METHODS UTILIZING THE SAME	OHTA, TOMOHIKO
<u>09646713</u>	<u>6565822</u>	150	09/21/2000	EPITAXIAL SILICON WAFER, METHOD FOR PRODUCING THE SAME AND SUBTRATE FOR EPITAXIAL SILICON WAFER	OHTA, TOMOHIKO
<u>09673480</u>	Not Issued	161	10/16/2000	Method for producing silicon single crystals	OHTA, TOMOHIKO
<u>09674858</u>	<u>6423285</u>	150	11/07/2000	Method for producing silicon single crystal and production apparatus therefor as well as crystal and silicon wafer produced by the method	OHTA, TOMOHIKO
<u>09727275</u>	<u>6482260</u>	150	11/30/2000	SILICON SINGLE CRYSTAL WAFER AND A METHOD FOR PRODUCING IT	OHTA, TOMOHIKO
<u>09937132</u>	<u>6632280</u>	150	09/21/2001	SINGLE CRYSTAL GROWING DEVICE	OHTA, TOMOHIKO
<u>09959381</u>	<u>6592662</u>	150	10/24/2001	METHOD FOR PREPARING	OHTA, TOMOHIKO

				SILICON SINGLE CRYSTAL AND SILICON SINGLE CRYSTAL	
<u>09959593</u>	<u>6605152</u>	150	10/31/2001	CATCH PAN FOR MELT LEAKAGE IN APPARATUS FOR PULLING SINGLE CRYSTAL	OHTA, TOMOHIKO
<u>09979519</u>	<u>6632411</u>	150	11/23/2001	SILICON WAFER AND METHOD FOR PRODUCING SILICON SINGLE CRYSTAL	OHTA, TOMOHIKO
<u>10204278</u>	<u>6764548</u>	150	08/20/2002	APPARATUS AND METHOD FOR PRODUCING SILICON SEMICONDUCTOR SINGLE CRYSTAL	OHTA, TOMOHIKO
<u>10204935</u>	<u>6913646</u>	150	08/27/2002	SILICON SINGLE CRYSTAL WAFER AND METHOD FOR PRODUCING SILICON SINGLE CRYSTAL	OHTA, TOMOHIKO
<u>10312921</u>	<u>6893499</u>	150	12/26/2002	SILICON SINGLE CRYSTAL WAFER AND METHOD FOR MANUFACTURING THE SAME	OHTA, TOMOHIKO
<u>10500580</u>	Not Issued	41	07/01/2004	AN SOI WAFER AND A METHOD FOR PRODUCING AN SOI WAFER	OHTA, TOMOHIKO
<u>10503721</u>	Not Issued	41	08/06/2004	HEATER FOR MANUFACTURING A CRYSTAL	OHTA, TOMOHIKO
<u>10510695</u>	Not Issued	41	10/08/2004	METHOD OF MANUFACTURING SILICON SINGLE CRYSTAL, SILICON SINGLE CRYSTAL AND SILICON WAFER	OHTA, TOMOHIKO
<u>10512470</u>	Not Issued	20	10/26/2004	Silicon single crystal wafer and epitaxial wafer, and method for producing silicon single crystal	OHTA, TOMOHIKO
<u>10561865</u>	Not Issued	30	02/20/2006	Method for producing single crystal and single crystal	OHTA, TOMOHIKO
<u>60127261</u>	Not Issued	159	03/31/1999	ISOLATION OF ROC1 AND ROC2	OHTA, TOMOHIKO
<u>60166927</u>	Not Issued	159	11/22/1999	ISOLATED DNA ENCODING CULLIN REGULATORS ROC1 AND ROC2, ISOLATED PROTEINS ENCODED BY SAME, AND METHODS UTILIZING THE SAME	OHTA, TOMOHIKO

*Applicants' Invention*



<a href="#">60541287</a>	Not Issued	159	02/02/2004	Tumor suppressor BRCA1-BARD1 ubiquitinates nucleophosmin and is inhibited by CDK2	OHTA, TOMOHIKO
<a href="#">60727429</a>	Not Issued	20	10/18/2005	Method for the ubiquitination of common subunits of RNA polymerases	OHTA, TOMOHIKO
<a href="#">60750877</a>	Not Issued	20	12/16/2005	Functional interaction between BRCA1 and HERC2, a large protein deficient in rjs/jdf2 mice x: BRCA1 degradation by HERC2	OHTA, TOMOHIKO
<a href="#">10261956</a>	<a href="#">6862014</a>	150	10/01/2002	DISPLAY DRIVING APPARATUS AND DRIVING CONTROL METHOD	OHTANI, TOMOHIKO
<a href="#">10415283</a>	Not Issued	30	04/28/2003	Display device and control system thereof	OHTANI, TOMOHIKO

Inventor Search Completed: No Records to Display.

<b>Search Another: Inventor</b>	<b>Last Name</b>	<b>First Name</b>	
	<input type="text" value="Ohta"/>	<input type="text" value="Tomohiko"/>	

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PALM INTRANET

## Inventor Name Search Result

Your Search was:

Last Name = FUSEGAWA

First Name = IZUMI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>06941624</u>	Not Issued	161	12/11/1986	METHOD AND APPARATUS FOR CZOCHRALSKI SINGLE CRYSTAL GROWING	FUSEGAWA, IZUMI
<u>07242414</u>	<u>4956153</u>	250	09/09/1988	APPARATUS FOR CZOCHRALSKI SINGLE CRYSTAL GROWING	FUSEGAWA, IZUMI
<u>07496750</u>	<u>5110404</u>	150	03/21/1990	METHOD FOR HEAT PROCESSING OF SILICON	FUSEGAWA, IZUMI
<u>07703750</u>	Not Issued	166	05/21/1991	METHOD FOR PULLING UP SEMICONDUCTOR SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>07713848</u>	<u>5306387</u>	150	06/12/1991	METHOD FOR PULLING UP SEMICONDUCTOR SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>07729026</u>	Not Issued	161	07/12/1991	METHOD FOR PULLING SEMICONDUCTOR SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>07796385</u>	<u>5688319</u>	150	11/22/1991	METHOD FOR TESTING ELECTRICAL PROPERTIES OF SILICON SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>07850506</u>	<u>5262338</u>	250	03/13/1992	METHOD FOR FABRICATION OF SEMICONDUCTOR DEVICE	FUSEGAWA, IZUMI
<u>07850915</u>	Not Issued	166	03/13/1992	HEAT TREATMENT OF SI SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>07850916</u>	<u>5386796</u>	150	03/13/1992	METHOD FOR TESTING QUALITY OF SILICON WAFER	FUSEGAWA, IZUMI
<u>07852612</u>	<u>5248378</u>	150	03/17/1992	METHOD AND APPARATUS FOR PRODUCING SILICON SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>07953918</u>	<u>5359959</u>	150	09/30/1992	METHOD FOR PULLING UP	FUSEGAWA, IZUMI

				SEMI-CONDUCTOR SINGLE CRYSTAL	
<u>07961182</u>	<u>5462010</u>	250	10/14/1992	APPARATUS FOR SUPPLYING GRANULAR RAW MATERIAL FOR A SEMICONDUCTOR SINGLE CRYSTAL PULLING APPARATUS	FUSEGAWA, IZUMI
<u>07961764</u>	<u>5373805</u>	250	10/15/1992	SINGLE CRYSTAL PULLING APPARATUS	FUSEGAWA, IZUMI
<u>08011744</u>	<u>5340434</u>	250	02/01/1993	PROCESS FOR PRODUCING SILICON SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>08012172</u>	<u>5361721</u>	250	02/02/1993	SINGLE CRYSTAL PULLING APPARATUS	FUSEGAWA, IZUMI
<u>08108285</u>	Not Issued	166	08/19/1993	HEAT TREATMENT OF SI SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>08190604</u>	Not Issued	166	02/02/1994	CRUCIBLE FOR PULLING SILICON SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>08238722</u>	<u>5534112</u>	150	05/05/1994	METHOD FOR TESTING ELECTRICAL PROPERTIES OF SILICON SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>08293214</u>	Not Issued	166	08/19/1994	APPARATUS FOR PRODUCING SILICON SINGLE CRYSTAL GROWN BY CZOCHRALSKI METHOD	FUSEGAWA, IZUMI
<u>08395837</u>	<u>5501172</u>	150	02/28/1995	METHOD OF GROWING SILICON SINGLE CRYSTALS	FUSEGAWA, IZUMI
<u>08445029</u>	Not Issued	166	05/19/1995	HEAT TREATMENT OF SI SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>08510436</u>	<u>5720809</u>	250	08/02/1995	CRUCIBLE FOR PULLING SILICON SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>08552164</u>	Not Issued	166	11/02/1995	APPARATUS FOR PRODUCING SILICON SINGLE CRYSTAL GROWN BY CZOCHRALSKI METHOD	FUSEGAWA, IZUMI
<u>08699719</u>	<u>5725661</u>	250	07/01/1996	EQUIPMENT FOR PRODUCING SILICON SINGLE CRYSTALS	FUSEGAWA, IZUMI
<u>08754784</u>	<u>5938841</u>	150	11/21/1996	DEVICE FOR PRODUCING SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>08760959</u>	<u>5766346</u>	150	12/05/1996	APPARATUS FOR PRODUCING SILICON SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>08770499</u>	<u>5851283</u>	150	12/20/1996	METHOD AND APPARATUS	FUSEGAWA, IZUMI

				FOR PRODUCTION OF SINGLE CRYSTAL	
<u>08773351</u>	<u>5871583</u>	150	12/26/1996	AN APPARATUS FOR PRODUCING SILICON CRYSTAL	FUSEGAWA, IZUMI
<u>08916291</u>	<u>5834322</u>	250	08/22/1997	HEAT TREATMENT OF SI SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>09270277</u>	<u>6153009</u>	150	03/16/1999	METHOD FOR PRODUCING A SILICON SINGLE CRYSTAL AND THE SILICON SINGLE CRYSTAL PRODUCED THEREBY	FUSEGAWA, IZUMI
<u>09290261</u>	<u>6117231</u>	150	04/13/1999	METHOD OF MANUFACTURING SEMICONDUCTOR SILICON SINGLE CRYSTAL WAFER	FUSEGAWA, IZUMI
<u>09429343</u>	<u>6387466</u>	150	10/28/1999	SINGLE-CRYSTAL SILICON WAFER	FUSEGAWA, IZUMI
<u>09646713</u>	<u>6565822</u>	150	09/21/2000	EPITAXIAL SILICON WAFER, METHOD FOR PRODUCING THE SAME AND SUBTRATE FOR EPITAXIAL SILICON WAFER	FUSEGAWA, IZUMI
<u>09673480</u>	Not Issued	161	10/16/2000	Method for producing silicon single crystals	FUSEGAWA, IZUMI
<u>09674858</u>	<u>6423285</u>	150	11/07/2000	Method for producing silicon single crystal and production apparatus therefor as well as crystal and silicon wafer produced by the method	FUSEGAWA, IZUMI
<u>09937132</u>	<u>6632280</u>	150	09/21/2001	SINGLE CRYSTAL GROWING DEVICE	FUSEGAWA, IZUMI
<u>09959381</u>	<u>6592662</u>	150	10/24/2001	METHOD FOR PREPARING SILICON SINGLE CRYSTAL AND SILICON SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>09979519</u>	<u>6632411</u>	150	11/23/2001	SILICON WAFER AND METHOD FOR PRODUCING SILICON SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>10204278</u>	<u>6764548</u>	150	08/20/2002	APPARATUS AND METHOD FOR PRODUCING SILICON SEMICONDUCTOR SINGLE CRYSTAL	FUSEGAWA, IZUMI
<u>10204935</u>	<u>6913646</u>	150	08/27/2002	SILICON SINGLE CRYSTAL WAFER AND METHOD FOR PRODUCING SILICON	FUSEGAWA, IZUMI

				SINGLE CRYSTAL	
<a href="#">10312921</a>	<a href="#">6893499</a>	150	12/26/2002	SILICON SINGLE CRYSTAL WAFER AND METHOD FOR MANUFACTURING THE SAME	FUSEGAWA, IZUMI
<a href="#">10500580</a>	Not Issued	41	07/01/2004	AN SOI WAFER AND A METHOD FOR PRODUCING AN SOI WAFER	FUSEGAWA, IZUMI
<a href="#">10510695</a>	Not Issued	41	10/08/2004	METHOD OF MANUFACTURING SILICON SINGLE CRYSTAL, SILICON SINGLE CRYSTAL AND SILICON WAFER	FUSEGAWA, IZUMI
<a href="#">10512470</a>	Not Issued	20	10/26/2004	Silicon single crystal wafer and epitaxial wafer, and method for producing silicon single crystal	FUSEGAWA, IZUMI
<a href="#">10516347</a>	Not Issued	20	11/30/2004	Graphite heater for producing single crystal, single crystal productin system and single crystal productin method	FUSEGAWA, IZUMI
<a href="#">10538878</a>	Not Issued	41	06/14/2005	Method of producing p-doped silicon single crystal and p-doped n-type silicon single crystal wafer	FUSEGAWA, IZUMI
<a href="#">10542376</a>	Not Issued	30	07/14/2005	AN SOI WAFER AND A METHOD FOR PRODUCING THE SAME	FUSEGAWA, IZUMI
<a href="#">10561865</a>	Not Issued	30	02/20/2006	Method for producing single crystal and single crystal	FUSEGAWA, IZUMI
<a href="#">10568186</a>	Not Issued	19	01/01/0001	Method for producing a single crystal and silicon single crystal wafer	FUSEGAWA, IZUMI

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**PALM INTRANET****Inventor Name Search Result**

Your Search was:

Last Name = SAKURADA


First Name = MASAHIRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>08498894</u>	<u>5609682</u>	150	07/06/1995	A METHOD FOR THE PREPARATION OF SILICON SINGLE CRYSTAL	SAKURADA, MASAHIRO
<u>08565100</u>	<u>5667584</u>	150	11/30/1995	METHOD FOR THE PREPARATION OF A SINGLE CRYSTAL OF SILICON WITH DECREASED CRYSTAL DEFECTS	SAKURADA, MASAHIRO
<u>08655810</u>	<u>5817171</u>	150	05/31/1996	APPARATUS AND METHOD FOR PRODUCING SINGLE CRYSTAL USING CZOCHRALSKI TECHNIQUE	SAKURADA, MASAHIRO
<u>08660198</u>	<u>5728211</u>	250	06/03/1996	SILICON SINGLE CRYSTAL WITH LOW DEFECT DENSITY AND METHOD OF PRODUCING SAME	SAKURADA, MASAHIRO
<u>08666654</u>	<u>5704973</u>	150	06/18/1996	AN APPARATUS AND METHOD FOR THE UNIFORM DISTRIBUTION OF CRYSTAL DEFECTS UPON A SILICON SINGLE CRYSTAL	SAKURADA, MASAHIRO
<u>08768282</u>	<u>5730800</u>	150	12/17/1996	FUSED SILICA GLASS CRUCIBLE	SAKURADA, MASAHIRO
<u>08798472</u>	<u>5948163</u>	250	02/10/1997	APPARATUS FOR MANUFACTURING CRYSTALS ACCORDING TO THE CZOCHRALSKI METHOD, AND CRYSTALS MANUFACTURED BY THE MANUFACTURING METHOD	SAKURADA, MASAHIRO
<u>09090400</u>	<u>5938842</u>	150	06/04/1998	METHOD FOR PRODUCING A SINGLE CRYSTAL USING CZOCHRALSKI TECHNIQUE	SAKURADA, MASAHIRO

<u>09125339</u>	<u>6071337</u>	150	08/13/1998	APPARATUS AND METHOD FOR PRODUCING CRYSTALS BY THE CZOCHRALSKI METHOD AND CRYSTALS PRODUCED BY THIS METHOD	SAKURADA, MASAHIRO
<u>09232561</u>	<u>6174364</u>	150	01/15/1999	METHOD FOR PRODUCING SILICON MONOCRYSTAL AND SILICON MONOCRYSTAL WAFER	SAKURADA, MASAHIRO
<u>09328278</u>	<u>6190452</u>	150	06/08/1999	SILICON SINGLE CRYSTAL WAFER AND METHOD FOR PRODUCING IT	SAKURADA, MASAHIRO
<u>09646713</u>	<u>6565822</u>	150	09/21/2000	EPITAXIAL SILICON WAFER, METHOD FOR PRODUCING THE SAME AND SUBSTRATE FOR EPITAXIAL SILICON WAFER	SAKURADA, MASAHIRO
<u>09727275</u>	<u>6482260</u>	150	11/30/2000	SILICON SINGLE CRYSTAL WAFER AND A METHOD FOR PRODUCING IT	SAKURADA, MASAHIRO
<u>10204935</u>	<u>6913646</u>	150	08/27/2002	SILICON SINGLE CRYSTAL WAFER AND METHOD FOR PRODUCING SILICON SINGLE CRYSTAL	SAKURADA, MASAHIRO
<u>10312921</u>	<u>6893499</u>	150	12/26/2002	SILICON SINGLE CRYSTAL WAFER AND METHOD FOR MANUFACTURING THE SAME	SAKURADA, MASAHIRO
<u>10500580</u>	Not Issued	41	07/01/2004	AN SOI WAFER AND A METHOD FOR PRODUCING AN SOI WAFER	SAKURADA, MASAHIRO
<u>10512470</u>	Not Issued	20	10/26/2004	Silicon single crystal wafer and epitaxial wafer, and method for producing silicon single crystal	SAKURADA, MASAHIRO
<u>10516347</u>	Not Issued	20	11/30/2004	Graphite heater for producing single crystal, single crystal productin system and single crystal productin method	SAKURADA, MASAHIRO
<u>10530557</u>	Not Issued	20	04/07/2005	Annealed wafer and anneald wafer manufacturing method	SAKURADA, MASAHIRO
<u>10538878</u>	Not Issued	41	06/14/2005	Method of producing p-doped silicon single crystal and p-doped n-type silicon single crystal wafer	SAKURADA, MASAHIRO
<u>10542376</u>	Not	30	07/14/2005	AN SOI WAFER AND A	SAKURADA,

	Issued			METHOD FOR PRODUCING THE SAME	MASAHIRO
<a href="#">10546693</a>	Not Issued	20	08/22/2005	An soi wafer and a method for producing the same	SAKURADA, MASAHIRO
<a href="#">10560581</a>	Not Issued	19	01/01/0001	Method for producing a single crystal and a single crystal	SAKURADA, MASAHIRO
<a href="#">10561205</a>	Not Issued	20	02/03/2006	Process for producing single crystal and single crystal	SAKURADA, MASAHIRO
<a href="#">10561865</a>	Not Issued	30	02/20/2006	Method for producing single crystal and single crystal	SAKURADA, MASAHIRO

**Inventor Search Completed:** No Records to Display.

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CONFIRMATION NO. 5511

<b>SERIAL NUMBER</b> 10/561,865	<b>FILING OR 371(c) DATE</b> 02/20/2006 <b>RULE</b>	<b>CLASS</b> 117	<b>GROUP ART UNIT</b> 1722	<b>ATTORNEY DOCKET NO.</b> 126363
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**APPLICANTS**

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 Atsushi Ozaki, Fukushima, JAPAN;

**\*\* CONTINUING DATA \*\*\*\*\***

This application is a 371 of PCT/JP04/07252 05/27/2004

**\*\* FOREIGN APPLICATIONS \*\*\*\*\***

JAPAN 2003-184838 06/27/2003

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\*\* 04/19/2006

Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWING</b> 9	<b>TOTAL CLAIMS</b> 20	<b>INDEPENDENT CLAIMS</b> 1
35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
Verified and Acknowledged <i>F. H.</i> Examiner's Signature Initials				

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**TITLE**

Method for producing single crystal and single crystal

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